## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Jiang et al.

Art Unit:

1765

Serial No.:

09/966,605

Examiner:

Vinh. L.

Filing Date:

09/28/2001

Docket No.: TI-31462

Title:

IN-SITU PLASMA ASH/TREATMENT AFTER VIA ETCH OF

LOW-K FILMS FOR POISON-FREE DUAL DAMASCENE

TRENCH PATTERNING

## REQUEST FOR EXTENSION OF TIME

Commissioner of Patents PO Box 1450 Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that the following papers are being transmitted by facsimile to the U.S. Patent and Trademark Office at

702-872-9318 on the date shown below:

ueline J. Darner, Reg. No. 36,144

September 9, 2003

Date

Pursuant to 37 CFR 1.136(a), Applicant(s) respectfully petitions the Commissioner for an extension of the shortened statutory period for response in the above-identified Application.

The fee for this extension is indicated below:

One Month (\$110)

X Two Months (\$410)

\_\_\_\_ Three Months (\$930)

Four Months (\$1,450)

Please charge the fee to deposit account no. 20-0668. Any further necessary extension of time is hereby requested. Charge any and all fees to deposit account no. 20-0668. An original and two copies of this sheet are enclosed.

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Respectiully Submitted,

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